

Supporting Information

for

Compact diode laser-based multi-photon polymerization system for 3D microfabrication with standard photoresist at high processing speeds

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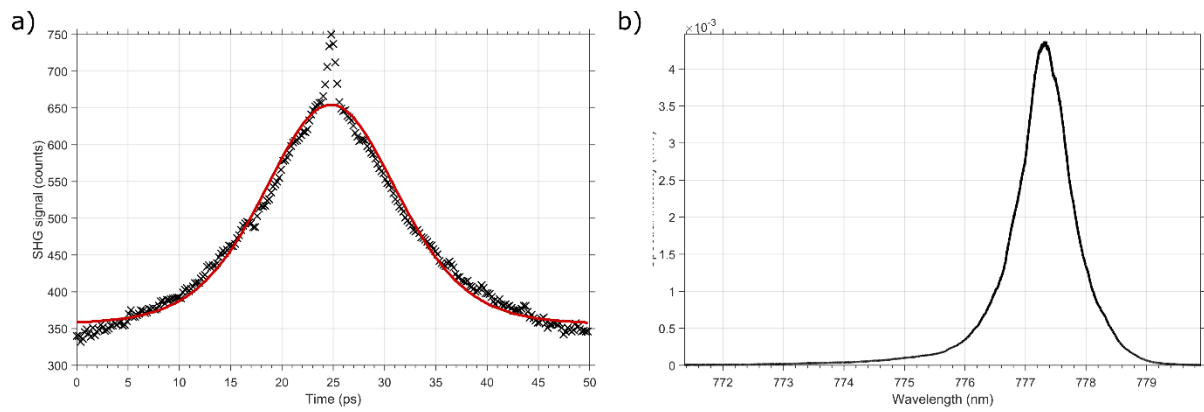


Figure S1: Measurement data of autocorrelation (a) and optical spectrum (b) of the diode laser

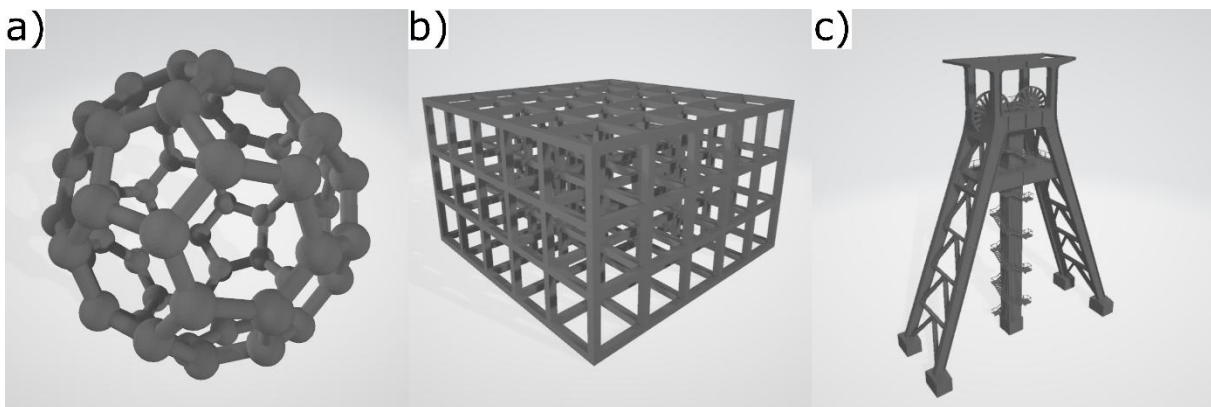


Figure S2: STL-models for 3D Structures fabricated by diode laser MPP (a fullerene molecule, b scaffold, c landmark mining tower of the city Bochum)

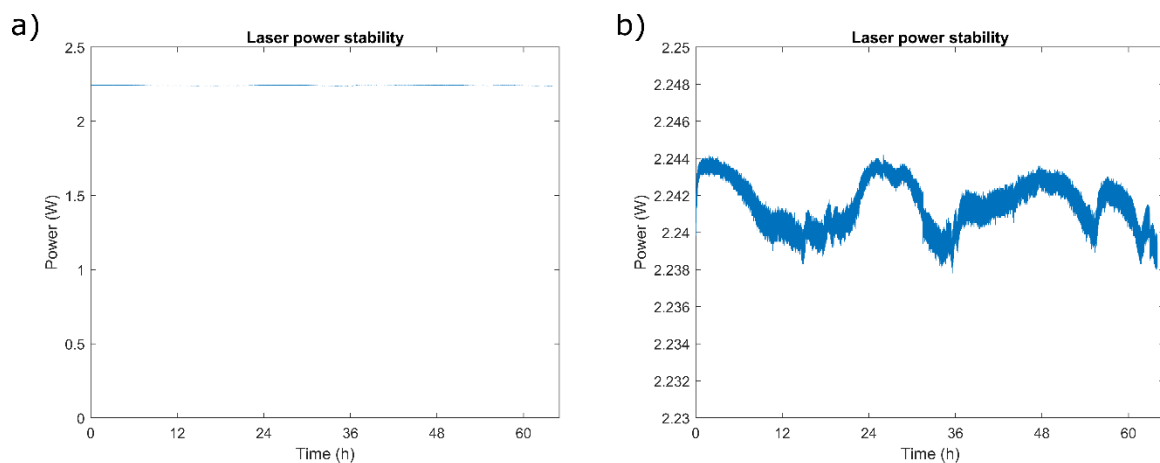


Figure S3: Laser power stability measurement over 64 h with different y-axis scales to identify the detail.